Attorney Docket Number	7276-78462-01
Application Number	10/777,282
Filing Date	February 10, 2004
First Named Inventor	Adams
Art Unit	1797
Examiner Name	Keri A. Moss

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

U.S. PATENT DOCUMENTS

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		3,715,911	February 13, 1973	CHUAN
		4,312,288	January 26, 1982	FINSTERWALDER ET AL.
		4,549,427	October 29, 1985	KOLESAR, JR.
		4,637,987	January 20, 1987	MINTEN *ET AL.*
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		4,935,634	June 19, 1990	HANSMA *ET AL.*
		4,992,244	February 12, 1991	GRATE
		5,266,801	November 30, 1993	ELINGS *ET AL.*
		5,345,213	September 6, 1994	SEMANCIK *ET AL.*
		5,356,756	October 18, 1994	CAVICCHI *ET AL.*
		5,411,709	May 2, 1995	FURUKI *ET AL.*
		5,412,980	May 9, 1995	ELINGS *ET AL.*
		5,445,008	August 29, 1995	WACHTER *ET AL.*
		5,469,369	November 21, 1995	ROSE-PEHRSSON *ET AL.*

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		5,519,212	May 21, 1996	ELINGS *ET AL.*
		5,719,324	February 17, 1998	THUNDAT *ET AL.*
		5,742,377	April 21, 1998	MINNE *ET AL.*
		5,750,989	May 12, 1998	LINDSAY *ET AL.*
		5,753,814	May 19, 1998	HAN *ET AL.*
		5,756,631	May 26, 1998	GRATE
		5,807,758	September 15, 1998	LEE *ET AL.*
		5,874,668	February 23, 1999	XU *ET AL.*
		5,883,705	March 16, 1999	*MINNE ET AL.*
		5,918,263	June 29, 1999	THUNDAT
		5,965,452	October 12, 1999	KOVACS
		6,005,400	December 21, 1999	THUNDAT *ET AL.*
		6,015,869	January 18, 2000	GRATE *ET AL.*
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		6,029,500	February 29, 2000	TOM
		6,032,518	March 7, 2000	PRATER *ET AL.*
		6,041,642	March 28, 2000	DUNCAN
		6,050,722	April 18, 2000	THUNDAT *ET AL.*
		6,075,585	June 13, 2000	MINNE *ET AL.*
		6,096,559	August 1, 2000	THUNDAT *ET AL.*

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		6,156,578	December 5, 2000	TOM
		6,167,748	January 2, 2001	BRITTON JR. *ET AL.*
		6,182,499	February 6, 2001	MCFARLAND *ET AL.*
		6,185,992	February 13, 2001	DANIELS *ET AL.*
		6,189,374	February 20, 2001	ADDERTON *ET AL.*
		6,212,939	April 10, 2001	THUNDAT
		6,253,162	June 26, 2001	JARMAN *ET AL.*
		6,263,736	July 24, 2001	THUNDAT *ET AL.*
		6,269,685	August 7, 2001	ODEN
		6,280,939	August 28, 2001	ALLEN
		6,289,717	September 18, 2001	THUNDAT *ET AL.*
		6,295,861	October 2, 2001	TOM *ET AL.*
		6,311,549	November 6, 2001	THUNDAT *ET AL.*
		6,311,557	November 6, 2001	DAVIS *ET AL.*
		6,312,959	November 6, 2001	DATSKOS
		6,336,353	January 8, 2002	MATSIEV *ET AL.*
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		6,393,895	May 28, 2002	MATSIEV *ET AL.*
		6,401,519	June 11, 2002	MCFARLAND *ET AL.*

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		6,411,075	June 25, 2002	BATTISTON *ET AL.*
		6,436,346	August 20, 2002	DOKTYCZ *ET AL.*
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		6,575,020	June 10, 2003	DE CHARMOY GREY *ET AL.*
		6,598,459	July 29, 2003	FU
		6,606,567	August 12, 2003	GRATE *ET AL.*
		6,650,102	November 18, 2003	HAJDUK *ET AL.*
		6,668,627	December 30, 2003	LANGE *ET AL.*

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		6,763,705	July 20, 2004	THUNDAT *ET AL.*
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		6,811,133	November 2, 2004	MILES
		6,815,866	November 9, 2004	LEE
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	Filing Date	February 10, 2004
	First Named Inventor	Adams
	Art Unit	1797
	Examiner Name	Keri A. Moss

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